3/7/1   (Item 1 from file: 351)
DIALOG(R)File 351:Derwent WPI
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014760205   **Image available**
WPI Acc No: 2002-580909/200262
Method for measuring skin condition
Patent Assignee: IDIPS LAB CO LTD (IDIP-N)
Inventor: AHN B G; KIM Y H
Number of Countries: 001 Number of Patents: 001
Patent Family:

Patent No	Kind	Date	Applicat No	Kind	Date	Week	
KR 2002017018	A	20020307	KR 200050072	A	20000828	200262	B

Priority Applications (No Type Date): KR 200050072 A 20000828
Patent Details:

Patent No	Kind	Lan	Pg	Main IPC	Filing Notes
KR 2002017018	A		1	A61B-010/00	

Abstract (Basic): KR 2002017018 A
    NOVELTY - Provided is a method for measuring skin condition which
allows accurate general evaluation of skin by examining skin condition
using differentiated condition listed according to various items and
quantitatively determining skin condition dominance of items and
secession from reference.
    DETAILED DESCRIPTION - The method comprises(S1) a step for
measuring ability to maintain moisture, (S2) a step for measuring a
level of oil secretion, (S3) a step for measuring regularity of oil on
skin surface, (S4) a step for measuring amount of melanin, (S5) a step
for measuring a level of partial melanin deposition on skin surface,
(S6) a step for measuring a pattern of corneum peeling, (S7) a step for
measuring a size of skin pores, (S8) a step for measuring acnes, (S9) a
step for measuring sensitivity of skin, (S10) assessing the skin
condition based on the measurements of (S1) to(S9).
    pp; 1 DwgNo 1/10
Derwent Class: P31
International Patent Class (Main): A61B-010/00
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METHOD FOR MEASURING SKIN CONDITION

Patent Number: KR2002017018

Publication date: 2002-03-07

Inventor(s): KIM YEONG HUN (KR); AHN BYEONG GIL (KR)

Applicant(s): IDIPS LAB CO LTD (KR)

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Priority Number(s): KR20000050072 20000828

IPC Classification: A61B10/00

EC Classification:

Equivalents:

Abstract